

Electronic Patent Application Fee Transmittal

Application Number:	09833711			
Filing Date:	13-Apr-2001			
Title of Invention:	Method of depositing optical quality silica films by PECVD while controlling gas pressure			
First Named Inventor:	Luc Ouellet			
Filer:	Richard J. Mitchell			
Attorney Docket Number:	10932-US			
Filed as Large Entity				
Utility Filing Fees				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
Pages:				
Claims:				
Miscellaneous-Filing:				
Petition:				
Patent-Appeals-and-Interference:				
Post-Allowance-and-Post-Issuance:				
Statutory disclaimer	1814	1	130	130
Extension-of-Time:				

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Miscellaneous:				
Total in USD (\$)				130